

HS/BCI2000	Description	Base rate	Bound rate	Implementation	ODCs
9010	Apparatus and equipment for photographic (including cinematographic) laboratories (including apparatus for the projection of circuit patterns on sensitized semi-conductor material), not specified or included elsewhere in this chapter, negatoscopes, projection screens:				
	- Apparatus for the projection or drawing of circuit patterns on sensitized semiconductor materials:				
901041000	-- Direct write-on-wafer apparatus	35	0	2001	0
901042000	-- Step and repeat aligners	35	0	2001	0
901049000	-- Other	35	0	2001	0
901050	-- Other apparatus and equipment for photographic (including cinematographic) laboratories; negatoscopes				
901050100	--- Apparatus for the projection or drawing of circuit patterns on sensitized flat panel displays substrates	35	0	2001	0
901050900	--- Other				
901090	- Parts and accessories				
901090100	-- Of apparatus of subheading 9010 41 00 0, 9010 42 00 0, 9010 49 00 0 or 9010 50 10 0	15	0	2001	0
901090900	-- Other				
9011	Compound optical microscopes, including those for photomicrography, cinephotomicrography or microprojection:				
901110	- Stereoscopic microscopes				
901110100	-- fitted with equipment specifically designed for the handling and transport of semiconductor wafers or reticles	10	0	2001	0
901110900	-- Other				
901120	- Other microscopes, for photomicrography, cinephotomicrography or micro-projection				
901120100	-- Fitted with equipment specifically designed for the handling and transport of semiconductor wafers or reticles	10	0	2001	0
901120900	-- Other				
901190	- Parts and accessories				
901190100	-- Of apparatus of subheadings 9011 10 10 0 or 9011 20 10 0	10	0	2001	0
901190900	-- Other				
9012	Microscopes other than optical microscopes, diffractio microscopes				
901210	- Microscopes other than optical microscopes and diffraction apparatus				
901210100	-- Electron beam microscopes fitted with equipment specifically designed for the handling and transport of semiconductor wafers or reticles	10	0	2001	0
901210900	-- Other				
901290	- Parts and accessories				
901290100	-- Of apparatus of subheading 9012 10 00 0	10	0	2001	0
901290900	-- Other				

HS/BCT2000	Description	Base rate	Bound rate	Implementation	ODCs
9013	Liquid crystal devices not constituting articles provided for more specifically in other headings; lasers, other than laser diodes; other optical appliances and instruments, not specified or included elsewhere in this Chapter:				
901380	- Other devices, appliances and instruments				
	-- Liquid crystal devices:				
901380200	--- Active matrix liquid crystal devices	35	0	2001	0
901380300	--- Other	35	0	2001	0
901380900	-- Other				
901390	- Parts and accessories				
901390100	--- For liquid crystal devices (LCD)	35	0	2001	0
901390900	--- Other				
9017	Drawing, marking-out or mathematical calculating instruments (for example, drafting machines, pantographs, protractors, drawing sets, slide rules, disc calculators); instruments for measuring length, for use in the hand (for example, measuring rods and tapes, micrometers, callipers), not specified or included elsewhere in this Chapter:				
901710	- Drafting tables and machines, whether or not automatic				
901710100	--- Plotters	35	0	2001	0
901710900	--- Other				
901720	- Other drawing, marking-out or mathematical calculating instruments				
901720050	--- Plotters	35	0	2001	0
	--- Other drawing instruments				
901720110	--- Drawing sets				
901720190	--- Other				
	--- Marking-out instruments				
901720310	--- Pattern generating apparatus of a kind used for producing masks or reticles from photoresist coated substrates	35	0	2001	0
901720390	--- Other				
901720900	-- Mathematical calculating instruments (including slide rules, disc calculators and the like)				
901790	- Parts and accessories				
901790100	-- For apparatus of subheading 9017 20 31 0	35	0	2001	0
901790900	-- Other				
9026	Instruments and apparatus for measuring or checking the flow, level, pressure or other variables of liquids or gases (for example, flow meters, level gauges, manometers, heat meters), excluding instruments and apparatus of heading No 9014, 9015, 9028 or 9032:				
902610	- For measuring or checking the flow or level of liquids				
902610100	--- For use in civil aircraft	0	0	2001	0
	--- Other				
	---- Electronic				

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902610510	---- Flow meters	35	0	2001	0
902610590	---- Other	35	0	2001	0
	--- Other				
902610910	----- Flow meters	35	0	2001	0
902610990	----- Other	35	0	2001	0
902620	- For measuring or checking pressure				
902620100	-- For use in civil aircraft	0	0	2001	0
	--- Other				
902620300	--- Electronic	35	0	2001	0
	--- Other				
	----- Spiral or metal diaphragm type pressure gauges				
902620510	----- Appliances for measuring and non-automatically regulating tyre pressure	35	0	2001	0
902620590	----- Other	35	0	2001	0
902620900	----- Other	35	0	2001	0
902680	- Other instruments or apparatus				
902680100	-- For use in civil aircraft	0	0	2001	0
	--- Other				
902680910	--- Electronic	35	0	2001	0
902680990	--- Other	35	0	2001	0
902690	- Parts and accessories				
902690100	-- For use in civil aircraft	0	0	2001	0
902690900	-- Other	35	0	2001	0
9027	<b>Instruments and apparatus for physical or chemical analysis (for example, polarimeters, refractometers, spectrometers, gas or smoke analysis apparatus); instruments and apparatus for measuring or checking viscosity, porosity, expansion, surface tension or the like; instruments and apparatus for measuring or checking quantities of heat, sound or light (including exposure meters); microtomes:</b>				
902720000	- Chromatographs and electrophoresis instruments	10.5	0	2001	0
902730000	- Spectrometers, spectrophotometers and spectrographs using optical radiations (UV, visible, IR)	9	0	2001	0
902750000	- Other instruments and apparatus using optical radiations (UV, visible, IR)	10.5	0	2001	0
902780	- Other instruments and apparatus				
	--- Electronic				
902780110	--- pH meters, rH meters and other apparatus for measuring conductivity	10.5	0	2001	0
902780130	--- Apparatus for performing measurements of the physical properties of semiconductor materials or of LCD substrates or associated insulating or and conducting layers during the semiconductor wafer production process or the LCD production process	10.5	0	2001	0
902780170	--- Other	10.5	0	2001	0
	--- Other				

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902780910	--- Visometers, porosimeters and expansion meters	10.5	0	2001	0
902780930	--- Apparatus for performing measurements of the physical properties of semiconductor materials or of LCD substrates or associated insulating or and conducting layers during the semiconductor wafer production process or the LCD production process	10.5	0	2001	0
902780970	--- Other	10.5	0	2001	0
902790	- Microtomes; parts and accessories				
902790100	-- Microtomes				
902790500	-- Part and accessories of apparatus of subheading 9027 20 to 9027 80	9	0	2001	0
902790800	-- Parts and accessories of microtomes or of gas or smoke analysis apparatus				
9030	<b>Oscilloscopes, spectrum analysers and other instruments and apparatus for measuring or checking electrical quantities, excluding meters of heading No 9028; instruments and apparatus for measuring or detecting alpha, beta, gamma, X-ray, cosmic or other ionizing radiations:</b>				
903040	- Other instruments and apparatus, specially designed for telecommunications (for example, cross-talk meters, gain measuring instruments, distortion factor meters, psophometers)				
903040100	-- For use in civil aircraft	0	0	2001	0
903040900	-- Other	10	0	2001	0
903082000	- Other instruments and apparatus				
903090	-- For measuring or checking semiconductor wafers or devices	10	0	2001	0
903090100	- Parts and accessories				
903090100	-- For use in civil aircraft				
903090200	-- For apparatus of subheading 9030 82 00 0	10	0	2001	0
903090800	-- Other				
9031	<b>Measuring or checking instruments, appliances and machines, not specified or included elsewhere in this chapter; profile projectors:</b>				
903141000	- Other optical instruments and appliances				
903141000	-- For inspecting semiconductor wafers or devices or for inspecting photomasks or reticles used in manufacturing semiconductor devices	10	0	2001	0
903149000	-- Other				
903149000	--- For measuring surface particulate contamination on semiconductor wafers	10	0	2001	0
903190	- Parts and accessories				
903190100	-- Of instruments, appliances and machines of subheading 9031 80, for use in civil aircraft				
903190200	-- For apparatus of subheadings 9031 41 00 0 and 9031 49 10 0	7	0	2001	0
903190800	-- Other				